



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Saburo KAMIYA

Group Art Unit: 2877

Application No.: 09/661,433

Examiner: S. Turner

Filed: September 13, 2000

Docket No.: 107312

For: EXPOSURE APPARATUS AND DEVICE PRODUCTION METHOD IN WHICH
POSITION OF REFERENCE PLATE PROVIDED ON SUBSTRATE STAGE IS
MEASURED (As Amended)

AMENDMENT UNDER 37 C.F.R. §1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the March 25, 2003 Office Action, the shortened statutory period for reply
being extended by the attached Petition for Extension of Time, the following is submitted:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.

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